장비번호	장비명	공정ID
SPRCE001	Mirror Projection Mask Aligner	SPRCOP001
SPRCE002	High resolution Raman spectrometer system	SPRCOP002
SPRCE003	FIB(Focused Ion Beam)	SPRCOP003
SPRCE004	Mask Aligner	SPRCOP004
SPRCE007	Rapid Thermal Annealing - Bosung	SPRCOP007
SPRCE008	Rapid Thermal Annealing Ⅰ	SPRCOP008
SPRCE009	Rapid Thermal Annealing Ⅱ	SPRCOP009
SPRCE010	CMP(Chemical-mechanical polishing)	SPRCOP010
SPRCE013	Alpha-Step (Step Height Measurement)	SPRCOP013
SPRCE014	Laser microscope	SPRCOP014
SPRCE015	Maskless photolithography system	SPRCOP015
SPRCE016	4-Point Probe System	SPRCOP016
SPRCE020	Deep etcher	SPRCOP020
SPRCE021	Elipsometer	SPRCOP021
SPRCE023	Wire bonder	SPRCOP023
SPRCE024	Wirebonder	SPRCOP024
SPRCE025	Atomic Force Microscope (AFM)	SPRCOP025
SPRCE026	Atomic Layer Deposition	SPRCOP026
SPRCE027	Wafer Scriber	SPRCOP027
SPRCE028	Wafer track	SPRCOP028
SPRCE029	Wet Station(acid)	SPRCOP029
SPRCE030	Wet Station(organic)	SPRCOP030
SPRCE032	Inductively Coupled Plasma/Reactive Ion Etching(Cl)-Tainics	SPRCOP032
SPRCE033	Inductively Coupled Plasma/Reactive Ion Etching(Cl)-Plasma Therm	SPRCOP033
SPRCE034	Inductively Coupled Plasma/Reactive Ion Etching(F)-Sorona	SPRCOP034
SPRCE035	Chemical Mechanical Planarization	SPRCOP035
SPRCE036	Metal Organic Chemical Vapor Deposition Ⅰ	SPRCOP036
SPRCE037	Ion sputter (SEM)	SPRCOP037
SPRCE038	Integrating spheres for UV/VIS spectrometer	SPRCOP038
SPRCE039	E-beam evaporator (ULVAC)	SPRCOP039
SPRCE040	E-beam Evaporator	SPRCOP040
SPRCE041	E-beam Evaporator - KVT	SPRCOP041
SPRCE042	Field Emission Scanning Electron Microscope	SPRCOP042
SPRCE043	Field Emission Scanning Electron Microscope - Hitachi	SPRCOP043
SPRCE045	Plasma Enhanced Chemical Vapor Deposition Ⅱ (BMR)	SPRCOP045
SPRCE046	Plasma Enhanced Chemical Vapor Deposition I (Oxford)	SPRCOP046
SPRCE048	Direct Current Sputtering System	SPRCOP048
SPRCE050	Spin Coater	SPRCOP050
SPRCE052	Radio Frequency Sputtering System Sputtering System Ⅱ	SPRCOP052

공정명	버전	의뢰기본
Mirror Projection Mask Aligner	1	0
High resolution Raman spectrometer system	1	0
FIB(Focused Ion Beam)	1	0
Mask Aligner	1	0
Rapid Thermal Annealing - Bosung	1	0
Rapid Thermal Annealing Ⅰ	1	0
Rapid Thermal Annealing Ⅱ	1	0
CMP(Chemical-mechanical polishing)	1	0
Alpha-Step (Step Height Measurement)	1	0
Laser microscope	1	0
Maskless photolithography system	1	0
4-Point Probe System	1	0
Deep etcher	1	0
Elipsometer	1	0
Wire bonder	1	0
Wirebonder	1	0
Atomic Force Microscope (AFM)	1	0
Atomic Layer Deposition	1	0
Wafer Scriber	1	20,000
Wafer track	1	0
Wet Station(acid)	1	0
Wet Station(organic)	1	0
Inductively Coupled Plasma/Reactive Ion Etching(Cl)-Tainics	1	0
Inductively Coupled Plasma/Reactive Ion Etching(Cl)-Plasma Therm	1	0
Inductively Coupled Plasma/Reactive Ion Etching(F)-Sorona	1	0
Chemical Mechanical Planarization	1	0
Metal Organic Chemical Vapor Deposition Ⅰ	1	0
Ion sputter (SEM)	1	0
Integrating spheres for UV/VIS spectrometer	1	0
E-beam evaporator (ULVAC)	1	0
E-beam Evaporator	1	0
E-beam Evaporator - KVT	1	0
Field Emission Scanning Electron Microscope	1	0
Field Emission Scanning Electron Microscope - Hitachi	1	0
Plasma Enhanced Chemical Vapor Deposition Ⅱ (BMR)	1	0
Plasma Enhanced Chemical Vapor Deposition I (Oxford)	1	0
Direct Current Sputtering System	1	0
Spin Coater	1	0
Radio Frequency Sputtering System Sputtering System Ⅱ	1	0

인건비	의뢰수가1	의뢰단위1	의뢰수가2	의뢰단위2	의뢰수가3	의뢰단위3	직접사용2	직접사용수
0	36,000	EA	0		0		24,000	0
0	24,000	EA	0		0		24,000	0
0	200,000	HOUR	0		0		160,000	0
0	36,000	EA	0		0		24,000	0
0	48,000	COUNT	0		0		32,000	0
0	48,000	COUNT	0		0		32,000	0
0	48,000	COUNT	0		0		32,000	0
0	112,000	EA	0		0		64,000	0
0	24,000	HOUR	0		0		24,000	0
0	24,000	HOUR	0		0		16,000	0
0	4,000	MINUTE	0		0		3,200	0
0	24,000	HOUR	0		0		0	0
0	160,000	COUNT	0		0		120,000	0
0	24,000	COUNT	0		0		24,000	0
0	36,000	HOUR	18,000	HOUR	0		24,000	0
0	36,000	HOUR	18,000	HOUR	0		24,000	0
0	70,000	HOUR	85,000	HOUR	0		35,000	0
0	80,000	COUNT	0		0		64,000	0
0	24,000	HOUR	0		0		2,000	0
0	24,000	EA	0		0		16,000	0
0	96,000	COUNT	0		0		72,000	0
0	96,000	COUNT	0		0		72,000	0
0	80,000	COUNT	0		0		56,000	0
0	80,000	COUNT	0		0		56,000	0
0	80,000	COUNT	0		0		51,000	0
0	112,000	EA	0		0		64,000	0
0	320,000	COUNT	0		0		240,000	0
0	10,000	COUNT	0		0		0	0
0	35,000	HOUR	0		0		25,000	0
0	120,000	COUNT	0		0		80,000	0
0	120,000	COUNT	0		0		80,000	0
0	120,000	COUNT	0		0		80,000	0
0	54,000	HOUR	24,000	EA	0		37,000	0
0	54,000	HOUR	0		0		37,000	0
0	80,000	COUNT	0		0		64,000	0
0	80,000	COUNT	0		0		64,000	0
0	64,000	EA	0		0		48,000	0
0	24,000	EA	0		0		16,000	0
0	0	EA	0		0		48,000	0

직접사용단	직접사용수	직접사용단	직접사용수	직접사용단	적용시작일
EA	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
MINUTE	0		0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
HOUR	12,000	HOUR	0		2025-07-01 09:00:00.0
HOUR	12,000	HOUR	0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
COUNT	0		0		2025-07-01 09:00:00.0
HOUR	16,000	EA	0		2025-07-01 09:00:00.0
HOUR	0		0		2025-07-01 09:00:00.0
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COUNT	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0
EA	0		0		2025-07-01 09:00:00.0

적용종료일	비고
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
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2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	파일변환 (분석 의뢰) + 40000원
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	1시간 초과 시 시간당 50% 추가
2099-12-31 12:59:00.0	1시간 초과 시 시간당 50% 추가
2099-12-31 12:59:00.0	수가 1 : AFM, DFM수가 2 : CAFM, KAFM
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	1시간 초과 시 시간당 50% 추가
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
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2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	수가 1 : FE-SEM수가 2 : EDS
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	
2099-12-31 12:59:00.0	